

# EUROPEAN PATENT OFFICE

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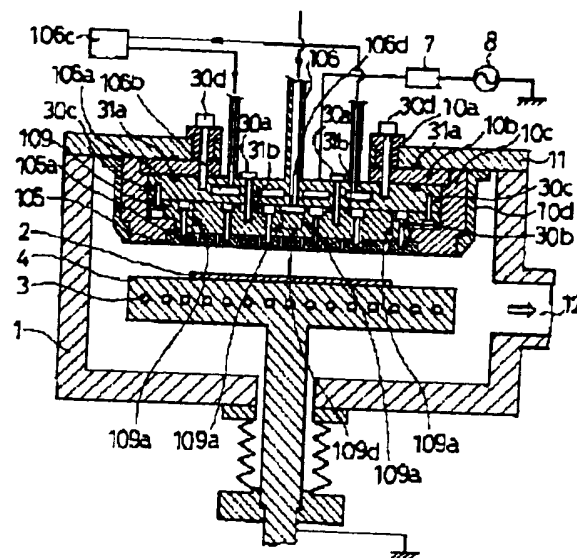
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TITLE : PLASMA TREATING DEVICE



ABSTRACT : PROBLEM TO BE SOLVED: To provide a plasma treating device by which the deformation of a gas blowing plate also serving as an upper electrode caused by heat does not occur, and plasma treatment for a large substrate is made possible.

SOLUTION: This plasma treating device has an evacuated chamber 1, a pair of counter electrodes 4 and 105 making treating gas into plasma state, a treating gas feeding means 106, a high frequency power source 8 and a heating means 3 heating the material 2 to be treated provided on the electrode 4. In this case, the side of the electrode 105 is constituted of a temp. controlling member 106a, a gas blowing plate 105 also serving as the electrode and having many gas blowing holes 105a at equal intervals, plural gas equalizing spaces 109a sandwiched between both, equalizing treating gas in the treating gas feeding means 106 and blowing out the gas from the gas blowing holes 105a and a heat transferring member 109 with a lattice shape transferring the heat of the gas blowing plate 105 also serving as the electrode to the temp. controlling member 106a.

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